

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant :	ASM MICROCHEMISTRY OY	)
App. No. :	See Appendix A	)
Filed :	See Appendix A	)
For :	See Appendix A	)
Examiner :	Unknown	)

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ESTABLISHMENT OF RIGHT OF ASSIGNEE TO TAKE ACTION  
AND  
REVOCATION AND POWER OF ATTORNEY

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

The undersigned is empowered to act on behalf of the assignee below (the "Assignee") with regard to the issued U.S. Patents and the U.S. Patent Applications listed on Appendix A, attached hereto. For each patent or patent Application listed in Appendix A the original Assignment(s) from the Inventors to ASM Microchemistry OY is recorded at the Reel and Frame numbers indicated or is attached. A true copy of the original Assignment of all listed patents and patent applications from ASM Microchemistry OY to the Assignee is also attached hereto and was submitted to the Assignment Division of the Office on December 17, 2003. This represents the entire chain from the Inventor(s) to the Assignee.

I declare that all statements made herein are true, and that all statements made upon information and belief are believed to be true, and further, that these statements were made with the knowledge that willful, false statements and the like so made are punishable by fine or imprisonment, or both, under 18 U.S.C. § 1001, and that willful, false statements may jeopardize the validity of the application, or any patent issuing thereon.

App. No. : See Appendix A  
Filed : See Appendix A

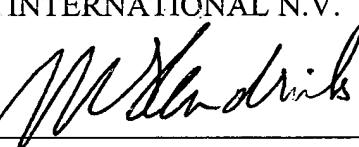
The undersigned hereby revokes any previous powers of attorney in the subject application, and hereby appoints the registrants of Knobbe, Martens, Olson & Bear, LLP, 2040 Main Street, Fourteenth Floor, Irvine, California 92614, Telephone (949) 760-0404, **Customer No. 20,995**, as its attorneys with full power of substitution and revocation to prosecute this application and to transact all business in the U.S. Patent and Trademark Office connected herewith. This appointment is to be to the exclusion of the inventor(s) and his attorney(s) in accordance with the provisions of 37 C.F.R. § 3.71.

Please use **Customer No. 20,995** for all communications.

ASM INTERNATIONAL N.V.

Dated: 18 Feb. 2004

By:

  
Menso Hendriks

Title: Central IP Officer

Address: Jan van Eycklaan 10  
3723 BC Bilthoven  
THE NETHERLANDS

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## APPENDIX A

<u>App. No.</u>	<u>Filing Date</u>	<u>Attorney Docket No.</u>	<u>Title</u>	<u>Patent No.</u>	<u>Assignment from Inventors to ASM Microchem. Reel/Frame</u>
09/686,613	1/4/00	SEPP1.001CP1	METHOD AND APPARATUS FOR GROWING THIN FILMS	6,630,030	011650/0441
09/581,020	6/7/00	SEPP2.001APC	METHOD FOR COATING INNER SURFACES OF EQUIPMENT	6,416,577	010951/0586
09/619,820	7/20/00	SEPP4.001AUS	METHOD FOR REMOVING SUBSTANCES FROM GASES	6,506,352	011694/0504
09/687,355	10/13/00	SEPP5.001AUS	METHOD FOR GROWING THIN OXIDE FILMS	6,632,279	011557/0134
09/749,339	12/27/00	SEPP6.001AUS	APPARATUS FOR GROWING THIN FILMS	6,551,406	011670/0177
09/749,329	12/27/00	SEPP7.001AUS	APPARATUS FOR GROWING THIN FILMS	6,447,607	011670/0191
09/764,692	1/18/01	SEPP8.001AUS	PROCESS FOR GROWING METALLOID THIN FILMS UTILIZING BORON-CONTAINING REDUCING AGENTS	6,599,572	011484/0029
09/835,737	4/16/01	SEPP10.001AUS	PROCESS FOR PRODUCING OXIDE THIN FILMS	6,548,424	012167/0702
09/800,757	3/6/01	ASMMC.002AUS	METHOD OF FORMING GRADED THIN FILMS USING ALTERNATING PULSES OF VAPOR PHASE REACTANTS	6,534,395	011798/0754
09/843,518	4/26/01	ASMMC.004AUS	PROTECTIVE LAYERS PRIOR TO ALTERNATING LAYER DEPOSITION	6,482,733	011766/0345
09/791,167	2/22/01	ASMMC.007AUS	METHOD OF FORMING ULTRATHIN OXIDE LAYER	6,492,283	011953/0233
09/568,077	5/10/00	ASMMC.012AUS	APPARATUS FOR FABRICATION OF THIN FILMS	6,562,140	011053/0323
09/769,562	1/25/01	ASMMC.012C1	APPARATUS FOR FABRICATION OF THIN FILMS	6,579,374	011053/0323
09/687,204	10/13/00	ASMMC.026AUS	DEPOSITION OF TRANSITION METAL CARBIDES	6,482,262	011505/0816
09/687,205	10/13/00	ASMMC.027AUS	PRODUCTION OF ELEMENTAL THIN FILMS USING A BORON-CONTAINING REDUCING AGENT	6,475,276	011505/0800

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10/205,296	7/24/02	SEPP4.001C1	METHOD AND APPARATUS FOR REMOVING SUBSTANCES FROM	Pending	011694/0504

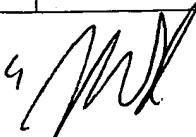
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			GASES		
10/618,429	7/10/03	SEPP5.001C1	METHOD FOR GROWING THIN OXIDE FILMS	Pending	011557/0134
10/365,926	2/13/03	SEPP6.001DV1	APPARATUS FOR GROWING THIN FILMS	Pending	011670/0177
10/205,297	7/24/02	SEPP7.001DV1	APPARATUS FOR GROWING THIN FILMS	Pending	011670/0191
10/394,309	3/20/03	SEPP8.001C1	PROCESS FOR GROWING METAL OR METAL CARBIDE THIN FILMS UTILIZING BORON-CONTAINING REDUCING AGENTS	Pending	011484/0029
09/787,062	6/28/01	SEPP9.001APC	METHOD FOR GROWING OXIDE THIN FILMS CONTAINING BARIUM AND STRONTIUM	Pending	011938/0097
09/836,674	4/16/01	SEPP11.001AUS	METHOD AND APPARATUS OF GROWING A THIN FILM ONTO A SUBSTRATE	Pending	012088/0322
10/270,745	10/11/02	SEPP11.001CP1	METHOD AND APPARATUS OF GROWING A THIN FILM	Pending	012088/0322
09/835,931	4/16/01	SEPP12.001AUS	METHOD OF GROWING A THIN FILM ONTO A SUBSTRATE	Pending	012029/0763
09/854,706	5/14/01	SEPP14.001AUS	METHOD AND APPARATUS FOR FEEDING GAS PHASE REACTANT INTO A REACTION CHAMBER	Pending	011811/0406
10/003,749	10/23/01	SEPP15.001AUS	PROCESS FOR PRODUCING ALUMINUM OXIDE FILMS AT LOW TEMPERATURES	Pending	012360/0374
10/066,315	1/29/02	SEPP16.001AUS	PROCESS FOR PRODUCING METAL THIN FILMS BY ALD	Pending	012950/0394
10/067,634	2/4/02	SEPP17.001AUS	METHOD OF DEPOSITING RARE EARTH OXIDE THIN FILMS	Pending	012573/0185 and 012913/0230
10/100,500	3/15/02	SEPP18.001AUS	METHOD FOR PREPARING METAL NITRIDE THIN FILMS	Pending	012711/0064
10/110,598	4/11/02	SEPP19.001APC	METHOD OF MODIFYING SOURCE CHEMICALS IN AN ALD PROCESS	Pending	013027/0564
10/110,730	4/11/02	SEPP20.001APC	METHOD OF DEPOSITING TRANSITION METAL NITRIDE THIN FILMS	Pending	013038/0940
10/148,525	8/27/02	SEPP21.001APC	METHOD OF GROWING OXIDE FILMS	Pending	013005/0964
10/276,663	11/15/02	SEPP22.001APC	PROCESS FOR PRODUCING INTEGRATED CIRCUITS	Pending	Copy Attached
10/333,521	1/17/03	SEPP23.001APC	METHOD OF GROWING A THIN FILM ONTO A SUBSTRATE	Pending	013967/0142
10/253,859	9/23/02	ASMMC.002C1	GRADED THIN FILMS	Pending	011798/0754
10/329,658	12/23/02	ASMMC.002DV1	GRADED THIN FILMS	Pending	011798/0754
10/237,526	9/6/02	ASMMC.004DV1	PROTECTIVE LAYERS PRIOR TO	Pending	011766/0345

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			ALTERNATING LAYER DEPOSITION		
10/303,355	11/21/02	ASMMC.4DV1C1	METHOD FOR CONTROLLING CONFORMALITY WITH ALTERNATING LAYER DEPOSITION	Pending	011766/0345
10/303,293	11/22/02	ASMMC.4DV1CP1	SEALING POROUS STRUCTURES	Pending	013888/0070
09/887,199	6/21/01	ASMMC.005AUS	METHOD OF FABRICATING TRENCH ISOLATION STRUCTURES FOR INTEGRATED CIRCUITS USING ATOMIC LAYER DEPOSITION	Pending	012472/0873
10/049,125	2/7/02	ASMMC.008APC	METHOD FOR DEPOSITING NANOLAMINATE THIN FILMS ON SENSITIVE SURFACES	Pending	013209/0629
10/383,291	3/6/03	ASMMC.012C2	APPARATUS FOR FABRICATION OF THIN FILMS	Pending	011053,0323
09/997,396	11/28/01	ASMMC.020AUS	THIN FILMS FOR MAGNETIC DEVICE	Pending	012562/0145
10/246,131	9/17/02	ASMMC.026C1	DEPOSITION OF TRANSITION METAL CARBIDES	Pending	011505/0816
10/210,715	7/30/02	ASMMC.027C1	PRODUCTION OF ELEMENTAL FILMS USING A BORON-CONTAINING REDUCING AGENT	Pending	011505/0800
09/945,463	8/31/01	ASMMC.029AUS	METHODS FOR MAKING A DIELECTRIC STACK IN AN INTEGRATED CIRCUIT	Pending	012303/0047
10/653,737	9/2/03	ASMMC.029DV1	METHODS FOR MAKING A DIELECTRIC STACK IN AN INTEGRATED CIRCUIT	Pending	012303/0047
09/801,542	3/7/01	ASMMC.030AUS	ALD REACTOR AND METHOD WITH CONTROLLED WALL TEMPERATURE	Pending	011610/0908
10/227,475	8/22/02	ASMMC.031AUS	LOW TEMPERATURE METHOD OF FORMING A GATE STACK WITH A HIGH K LAYER DEPOSITED OVER AN INTERFACIAL OXIDE LAYER	Pending	013897/0346
10/136,095	4/30/02	ASMMC.032AUS	METHOD OF DEPOSITING THIN FILMS FOR MAGNETIC HEADS	Pending	013660/0588
10/007,304	12/5/01	ASMMC.033AUS	COPPER INTERCONNECT STRUCTURE HAVING STUFFED DIFFUSION BARRIER	Pending	012874/0783
10/066,169	1/30/02	ASMMC.034AUS	ACTIVE PULSE MONITORING IN A CHEMICAL REACTOR	Pending	012570/0319
10/187,142	6/28/02	ASMMC.035AUS	SOURCE CHEMICAL CONTAINER ASSEMBLY	Pending	013369/0749
09/975,466	10/9/01	ASMMC.036AUS	IN SITU REDUCTION OF COPPER OXIDE PRIOR TO SILICON CARBIDE DEPOSITION	Pending	012382/0183 and 012644/0307
10/222,005	8/14/02	ASMMC.037AUS	ATOMIC LAYER DEPOSITION REACTOR	Pending	013590/0973

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10/242,368	9/12/02	ASMMC.038AUS	METAL NITRIDE DEPOSITION BY ALD WITH REDUCTION PULSE	Pending	013590/0968
10/285,348	10/30/02	ASMMC.042AUS	METHOD OF MONITORING EVAPORATION RATE OF SOURCE MATERIAL IN A CONTAINER	Pending	013788/0317

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